



PATENT  
Atty. Dkt. AMAT/6218/DD/LOW K/JW

1762 #2  
BT  
7-19-02

# IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:  
Lang et al.

Serial No.: 10/092,203

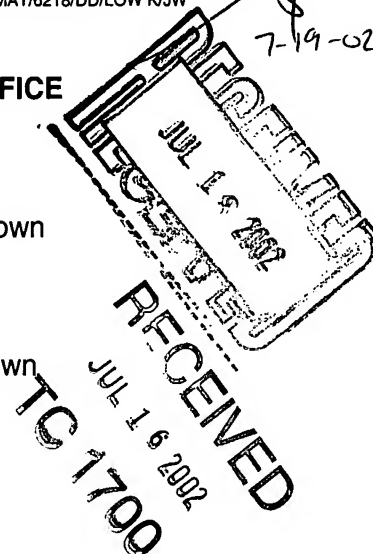
Confirmation No.: Unknown

Filed: March 4, 2002

For: A Method of Depositing a  
Low k Dielectric Barrier  
Film for Copper  
Damascene Application

Group Art Unit: Unknown

Examiner: Unknown



Commissioner for Patents  
Washington, D.C. 20231

Dear Sir:

CERTIFICATE OF MAILING 37 CFR 1.8	
I hereby certify that this correspondence is being deposited on June 25, 2002 with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, Washington, D.C. 20231.	
6/25/02 Date	<i>Kent R. Z...</i> Signature

## INFORMATION DISCLOSURE STATEMENT

The Applicants, and the Attorney who signs below on the basis of the information supplied by the inventor and the information in his file, submit herewith patents, publications, or other information of which they are aware, which may be material to the examination of this application and in respect of which there may be a duty to disclose in accordance with 37 CFR § 1.56.

While the information submitted in this Information Disclosure Statement may be material pursuant to 37 CFR § 1.56, it is not intended to constitute an admission that any patent, publication, or other information referred to therein is prior art for this invention unless specifically designated as such.

In accordance with 37 CFR § 1.97, this Information Disclosure Statement is not to be construed as a representation that a search has been made or that no other possibly material information as defined under 37 CFR § 1.56(a) exists.

The patents and/or publications submitted herewith are set forth on the attached Form PTO-1449.

If the sum of \$180.00 is due under 37 CFR § 1.17(p) pursuant to § 1.97, the Commissioner is hereby authorized to charge this fee, and any other fee necessary to make this submission timely, to the Deposit Account No. 20-0782/AMAT/6218/DD/LOW K/JW.

Respectfully submitted,



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U.S. Department of Commerce, Patent and Trademark Office (PTO Form 1449 modified)					Docket No. AMAT/6218/DD/LOW K/JW		Serial No. 10/092,203	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT					Applicant Lang et al.		Confirmation No.: Unknown	
(Use several sheets if necessary)					Filing Date March 4, 2002		Group Unknown	
Examiner Unknown								
<b>U.S. Patent Documents</b>								
*Examiner Initial		Document Number	Issue Date	Applicant(s) Name	Class	Subclass	Filing Date If Appropriate	
	A1	6,312,793	11/06/2001	Grill et al.	428	312.6	05/26/1999	
	A2	6,287,990	09/11/2001	Cheung et al.	438	780	09/29/1998	
	A3	6,159,871	12/12/2000	Loboda et al.	438	786	05/29/1998	
	A4	6,147,009	11/14/2000	Grill et al.	438	780	06/29/1998	
	A5	6,051,321	04/18/2000	Lee et al.	428	447	10/24/1997	
	A6	5,989,998	11/23/1999	Sugahara et al.	438	623	08/28/1997	
	A7	5,818,071	10/06/1998	Loboda et al.	257	77	02/02/1995	
	A8	5,711,987	01/27/1998	Bearinger et al.	427	7	10/04/1996	
	A9	5,465,680	11/14/1995	Loboda	117	84	07/01/1993	
	A10							
	A11							
	A12							
<b>Foreign Patent Documents</b>								
*Examiner Initial		Document Number	Date	Country	Class	Subclass	Translation	
							YES	NO
	B1						<input type="checkbox"/>	<input type="checkbox"/>
	B2						<input type="checkbox"/>	<input type="checkbox"/>
<b>OTHER ART</b>								
*Examiner Initial		Including Author, Title, Date, Pertinent Pages, Etc.						
	C1	Huang, et al., USSN 09/902,518, filed July 10, 2001, "Method and Apparatus for Treating Low <i>k</i> Dielectric Layers to Reduce Diffusion"						
	C2	Campana, et al., USSN 09/793,818, filed Feb. 23, 2001, "Method of Depositing Low Dielectric Constant Silicon Carbide Layers"						
	C3	Nemani, et al., USSN 09/627,667, filed July 28, 2000, "Method of Depositing Dielectric Films"						
Examiner					Date Considered			
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.								

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